AMENDMENTS TO THE CLAIMS:

Kindly amend claims 1-4, and add claim 5, as shown below.

This listing of claims will replace all prior versions and listings of claims in the Application:

Claim 1 (currently amended). A noncontact conductivity measuring instrument for noncontact measurement of conductivity of a silicon wafer using a microwave, the noncontact conductivity measuring instrument characterized by including comprising:

an oscillator which performs oscillation of for oscillating the microwave;

a circulator which is connected to the oscillator;

a horn antenna which is connected to the circulator, the horn antenna transmitting the microwave to a sample the silicon wafer and receiving a reflected wave from a surface of the silicon wafer;

a detector which is connected to said circulator, the detector outputting a voltage proportional to a square of magnitude of the received microwavereflected wave; and

<u>a computer for computing means for inputting said voltage to compute</u> computing conductivity <u>of said silicon wafer from said voltage</u>.

Claim 2 (currently amended). A noncontact conductivity measuring instrument according to claim 1, characterized in that wherein said circulator is in contact with connected to the oscillator through an isolator.

Claim 3 (currently amended). A noncontact conductivity measuring instrument according to claim 1, characterized in that wherein a frequency of the microwave oscillating in said oscillator is 94 GHzwhen a silicon wafer is measured.

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Claim 4 (currently amended). A noncontact conductivity measuring instrument according to claim 2, characterized in that wherein a frequency of the microwave oscillating in said oscillator is 94 GHz-when a silicon wafer is measured.

Claim 5 (new). A conductivity measuring instrument for noncontact measuring of conductivity of a silicon wafer using a microwave, the measuring instrument comprising, in combination:

an oscillator for oscillating of the microwave;

a circulator connected to the oscillator;

a horn antenna connected to the circulator, the horn antenna transmitting the microwave to the silicon wafer and receiving a reflected wave from a surface of the silicon wafer;

a detector connected to said circulator, the detector outputting a voltage proportional to a square of magnitude of the reflected wave; and

a computer for computing conductivity of said silicon wafer from said voltage.

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